We claim:

1	1.	A microsensor for sensing a substance comprising:
2		a substrate;
3		a source of light;
4		an optical microresonator fabricated in the substrate exposed to the
5	substance to allow an interaction between the microresonator and substance;	
3		a waveguide coupling the source of light to the optical microresonator; and
7		a detector coupled to the microresonator to measure a performance
3	parameter of the optical microresonator sensitive $t\varepsilon$ interaction of the substance	
9	with the optical microresonator.	
1	2.	The microsensor of claim 1 further comprising a polymer coating disposed
2	on the	e microresonator, which polymer coating is reactive with the substance.
1	3.	The microsensor of claim 1 where the microresonator is a semiconductor
2	optical ring microresonator.	
1	4.	The microsensor of claim 1 where the microresonator has an initial Q of
2	10,000 or greater.	

- 1 5. The microsensor of claim 1 where the performance parameter is the
- 2 resonant frequency of the microresonator.
- 1 6. The microsensor of claim 1 where the performance parameter is the
- 2 absorption loss of whispering gallery modes in the microresonator.
- 1 7. The microsensor of claim 1 where the performance parameter is the
- 2 quality factor of the microresonator.
- 1 8. The microsensor of claim 1 where the detector is a germanium detector
- 2 and the substrate is a silicon-on-insulator (SOI) heterostructure.
- 1 9. The microsensor of claim 8 further comprising CMOS integrated read-out
- 2 circuitry fabricated in the substrate and coupled to the germanium detector.
- 1 10. The microsensor of claim 1 where the detector comprises a read-out optic
- 2 fiber coupled to a grating coupler.
- 1 11. The microsensor of claim 1 further comprising a plurality of
- 2 microresonators and a corresponding plurality of detectors formed into an array
- 3 coupled by the waveguide to the light source in which the plurality of
- 4 microresonators are exposed to a plurality of substances.

- 1 12. The microsensor of claim 11 further comprising an addressing circuit for
- 2 reading the array.
- 1 13. The microsensor of claim 12 further comprising CMOS integrated read-out
- 2 circuitry fabricated in the substrate coupled to the addressing circuit.
- 1 14. The microsensor of claim 1 where the detector comprises a polycrystalline
- 2 germanium detector fabricated proximate to the microresonator.
- 1 15. The microsensor of claim 1 where the detector is deposited onto the
- 2 waveguide during a post-processing step following CMOS fabrication of the
- 3 waveguide.
- 1 16. The microsensor of claim 1 further comprising a microfluidic circuit for
- 2 communicating the substance to the microresonator.
- 1 17. The microsensor of claim 16 where the microfluidic circuit comprises
- 2 pneumatic valves and peristaltic pumps defined by multi-layer replication
- 3 lithography for delivering picoliter volumes of the substance to the
- 4 microresonator.

- 1 18. The microsensor of claim 1 where the microresonator is characterized by
- 2 an optical absorption loss determined by direct optical excitation of the substance
- 3 when in contact with the microresonator.
- 1 19. The microsensor of claim 18 further comprising a plurality of
- 2 microresonators corresponding to a plurality of different resonant frequencies to
- 3 generate an absorption spectrum of the substance.
- 1 20. The microsensor of claim 2 where the coating reacts with the substance to
- 2 form an altered optical parameter which in turn alters an optical parameter of the
- 3 microresonator.
- 1 21. The microsensor of claim 20 where the altered optical parameter is the
- 2 refractive index of the coating or the waveguide loss of the microresonator.
- 1 22. The microsensor of claim 20 where the coating reacts only with the
- 2 substance.
- 1 23. The microsensor of claim 22 where the coating is reacts only with the
- 2 substance by means of an enzyme linked immunosorbent assay (ELISA).

- 1 24. The microsensor of claim 2 further comprising a microfountain pen and
- where the coating is applied to the microresonator by the microfountain pen.
- 1 25. The microsensor of claim 2 further comprising an elastomeric flow channel
- 2 in communication with the microresonator and where the coating is applied to the
- 3 microresonator by a functionalization treatment by means of the elastomeric flow
- 4 channel.
- 1 26. The microsensor of claim 1 further comprising a plurality of microsensors
- 2 organized in an addressable array on the substrate, ones of the plurality of
- 3 microsensors being resonant at or tuned to different optical frequencies,
- 4 absorption losses of the plurality of microsensors being measured as a result of
- 5 optical coupling between an analyte and ones of the resonators as determined by
- 6 the resonant frequency of the microresonator and the absorption peak of the
- 7 analyte, whereby an absorption spectrum of direct spectroscopy of an analyte or
- 8 absorption of antibody-linked fluorescent molecules used as markers are
- 9 measured.
- 1 27. The microsensor of claim 1 further comprising a plurality of microsensors
- 2 organized in an addressable array on the substrate, the plurality of corresponding
- 3 resonators having a selectively pretreated surface, a change in refractive index
- 4 or waveguide loss of ones of the plurality of resonators arising as a result of
- 5 selective attachment of an analyte to the pretreated surface being measured.

- 1 28. The microsensor of claim 1 where the substrate is a silicon-on-insulator
- 2 (SOI) substrate, where the waveguide and microresonator are fabricated on the
- 3 substrate by means of SOI processes and where the detector is fabricated on the
- 4 substrate by means of CMOS fabrication processes.
- 1 29. The microsensor of claim 1 where the source of light comprises an
- 2 external laser.
- 1 30. The microsensor of claim 1 where the source of light comprises a filtered
- 2 tungsten filament lamp, a filtered broad-band light emitting diode, a Fabry-Perot
- 3 cleaved cavity laser, a vertical cavity surface emitting (VeSEL), or a grating
- 4 coupled surface emitting laser directly bonded onto the substrate.
- 1 31. The microsensor of claim 13 where the CMOS integrated read-out circuitry
- 2 provides diagnostic information on the condition of sensor performance and
- 3 electronic intelligence in the read-out process.
- 1 32. The microsensor of claim 31 further comprising a wireless interface
- 2 fabricated on the substrate and communicated to the read-out circuitry.
- 1 33. A method for sensing a substance comprising:
- 2 providing a substrate;

- 3 providing a source of light;
- 4 communicating the light through a waveguide coupled to the source of
- 5 light to an optical microresonator fabricated in the substrate exposed to the
- 6 substance to allow an interaction between the microresonator and substance;
- 7 and
- 8 detecting the interaction between the microresonator and substance by
- 9 measurement of a performance parameter of the optical microresonator.
- 1 34. The method of claim 33 further comprising disposing a polymer coating on
- 2 the microresonator, which polymer coating is selectively reactive with the
- 3 substance.
- 1 35. The method of claim 33 where detecting the interaction between the
- 2 microresonator and substance comprising detecting the optical performance of a
- 3 semiconductor optical ring microresonator.
- 1 36. The method of claim 35 where detecting the optical performance of a
- 2 semiconductor optical ring microresonator comprises measuring the optical
- 3 performance of a microresonator with an initial Q of 10,000 or greater.

- 1 37. The method of claim 36 where measuring the optical performance of a
- 2 microresonator comprises measuring the resonant frequency of the
- 3 microresonator.
- 1 38. The method of claim 36 where measuring the optical performance of a
- 2 microresonator comprises measuring the absorption loss of whispering gallery
- 3 modes in the microresonator.
- 1 39. The method of claim 36 where measuring the optical performance of a
- 2 microresonator comprises measuring the quality factor of the microresonator.
- 1 40. The method of claim 33 where detecting the interaction between the
- 2 microresonator and substance comprises detecting the optical output of the
- 3 microresonator with a germanium detector and where providing the substrate
- 4 comprises providing a silicon-on-insulator (SOI) heterostructure.
- 1 41. The method of claim 33 further comprising fabricating CMOS integrated
- 2 read-out circuitry in the substrate corresponding to each microresonator.
- 1 42. The method of claim 33 where detecting the interaction between the
- 2 microresonator and substance comprises coupling light from the microresonator
- 3 to a read-out optic fiber coupled to a grating coupler.

- 1 43. The method of claim 33 further comprising providing a plurality of
- 2 microresonators and a corresponding plurality of detectors configured into an
- 3 array coupled by the waveguide to the light source and exposing the plurality of
- 4 microresonators to the substance or plurality of substances.
- 1 44. The method of claim 43 further comprising fabricating an addressing
- 2 circuit on the substrate for reading the array.
- 1 45. The method of claim 44 further comprising fabricating CMOS integrated
- 2 read-out circuitry in the substrate coupled to the addressing circuit.
- 1 46. The method of claim 33 where detecting the interaction between the
- 2 microresonator and substance comprises detecting the interaction with a
- 3 polycrystalline germanium detector fabricated proximate to the microresonator.
- 1 47. The method of claim 46 further comprising fabricating the waveguide with
- 2 CMOS processes and fabricating the detector in communication with the
- 3 waveguide during a post-processing step following CMOS fabrication of the
- 4 waveguide.
- 1 48. The method of claim 33 further comprising providing a microfluidic circuit
- 2 for communicating the substance to the microresonator.

- 1 49. The method of claim 48 where providing a microfluidic circuit comprises
- 2 fabricating pneumatic valves and peristaltic pumps by multi-layer replication
- 3 lithography for delivering picoliter volumes of the substance to the
- 4 microresonator.
- 1 50. The method of claim 33 where detecting the interaction between the
- 2 microresonator and substance comprises measuring an optical absorption loss of
- 3 the microresonator arising from direct optical excitation of the substance when in
- 4 contact with the microresonator.
- 1 51. The method of claim 50 further comprising a steeting the interaction
- 2 between the microresonator and substance at a plurality of microresonators
- 3 corresponding to a plurality of different resonant frequencies to generate an
- 4 absorption spectrum of the substance.
- 1 52. The method of claim 34 further comprising selectively reacting the coating
- 2 with the substance to alter an optical parameter of the microresonator.
- 1 53. The method of claim 52 where reacting the coating with the substance
- 2 comprise altering the refractive index of the coating or the waveguide loss of the
- 3 microresonator.

- 1 54. The method of claim 52 where selectively reacting the coating with the
- 2 substance comprises reacting only with the substance.
- 1 55. The method of claim 54 where reacting only with the substance comprises
- 2 reacting only with the substance by means of an enzyme linked immunosorbent
- 3 assay (ELISA).
- 1 56. The method of claim 34 further comprising applying the coating to the
- 2 microresonator by means of a microfountain pen.
- 1 57. The method of claim 34 further comprising applying the coating to the
- 2 microresonator by means of an elastomeric flow channel in communication with
- 3 the microresonator.
- 1 58. The method of claim 33 further comprising providing a plurality of
- 2 microsensors organized in an addressable array or, the substrate, ones of the
- 3 plurality of microsensors being resonant at or tuned to different optical
- 4 frequencies, measuring the absorption losses of the plurality of microsensors as
- 5 a result of optical coupling between an analyte and ones of the resonators as
- 6 determined by the resonant frequency of the microresonator and the absorption
- 7 peak of the analyte, and generating an absorption spectrum of direct

- 8 spectroscopy of an analyte or absorption of antibody-linked fluorescent
- 9 molecules used as markers are measured.
- 1 59. The method of claim 33 further comprising providing a plurality of
- 2 microsensors organized in an addressable array on the substrate, the plurality of
- 3 corresponding resonators having a selectively pretreated surface, changing the
- 4 refractive index or waveguide loss of ones of the plurality of resonators as a
- 5 result of selective attachment of an analyte to the pretreated surface and
- 6 measuring the change the refractive index or waveguide loss to generate an
- 7 assay of the substance.
- 1 60. The method of claim 33 where providing the substrate provides a silicon-
- 2 on-insulator (SOI) substrate, and further comprising fabricating the waveguide
- 3 and microresonator on the substrate by means of SOI processes and fabricating
- 4 the detector on the substrate by means of CMOS fabrication processes.
- 1 61. The method of claim 33 where providing the source of light comprises
- 2 providing an external laser.
- 1 62. The method of claim 33 where providing the source of light comprises
- 2 providing a filtered tungsten filament lamp, a filtered broad-band light emitting
- 3 diode, a Fabry-Perot cleaved cavity laser, a vertical cavity surface emitting

- 4 (VeSEL), or a grating coupled surface emitting laser directly bonded onto the
- 5 substrate.
- 1 63. The method of claim 45 further comprising generating diagnostic
- 2 information on the condition of sensor performance and electronic intelligence by
- 3 means of the integrated read-out circuitry.
- 1 64. The method of claim 45 further comprising fabricating a wireless interface
- 2 on the substrate communicated to the read-out circuitry.